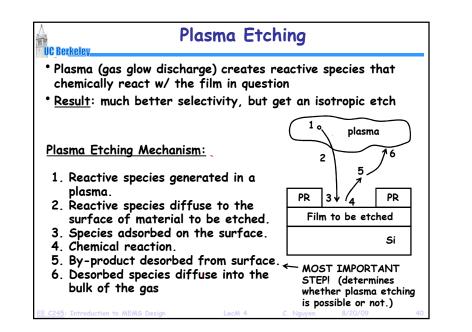
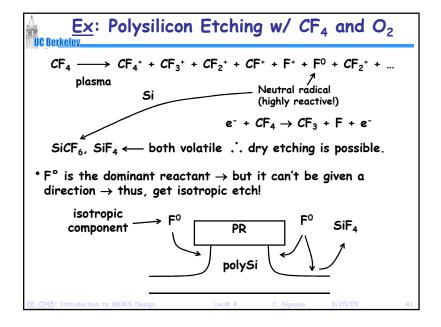
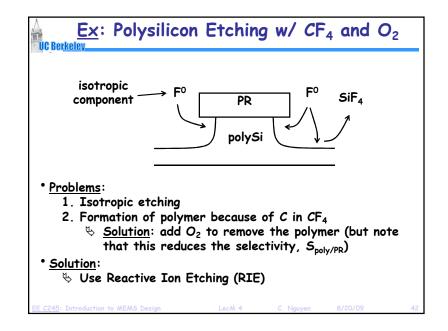
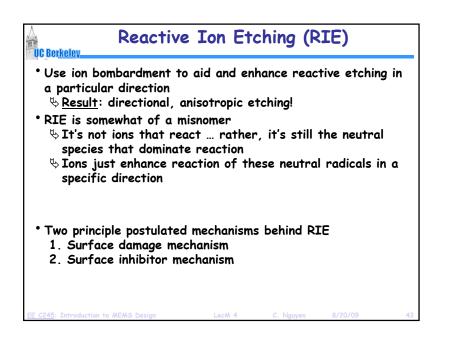


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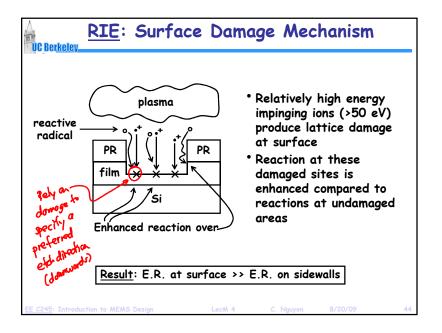


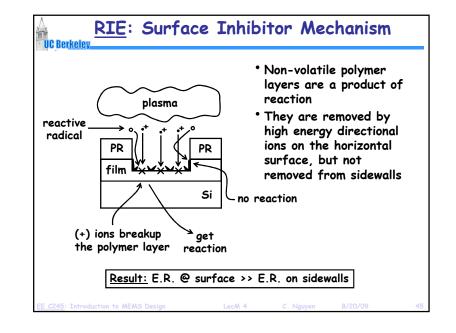


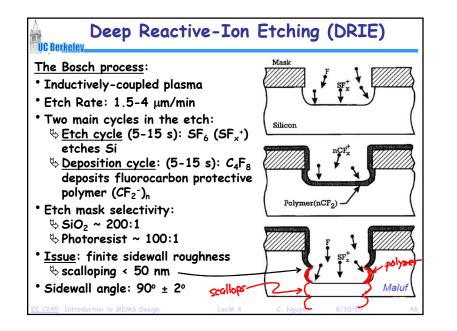
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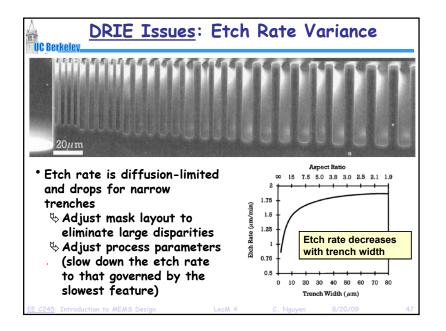
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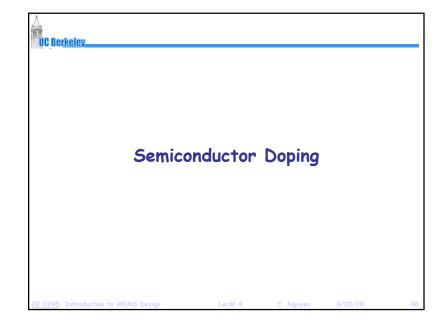


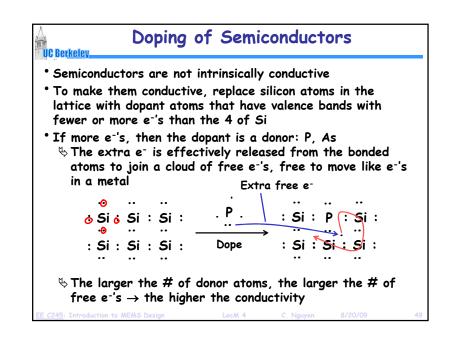


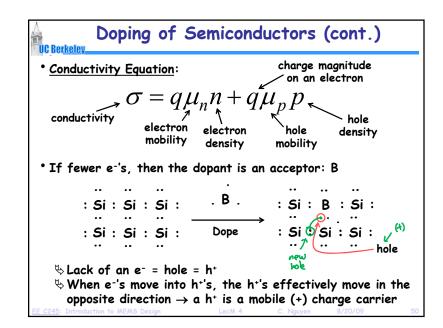


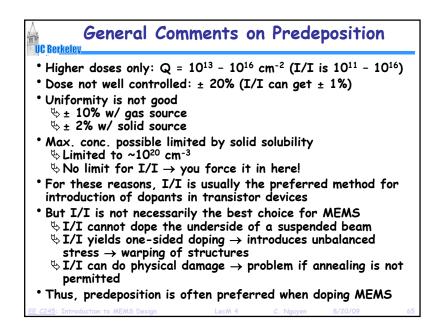
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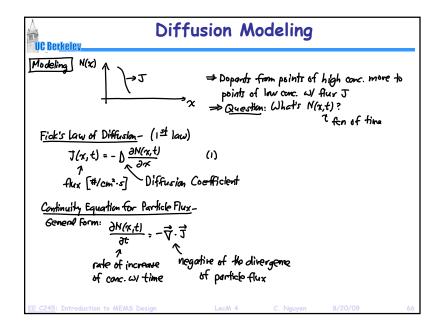


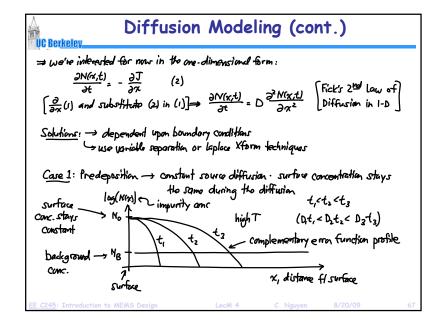


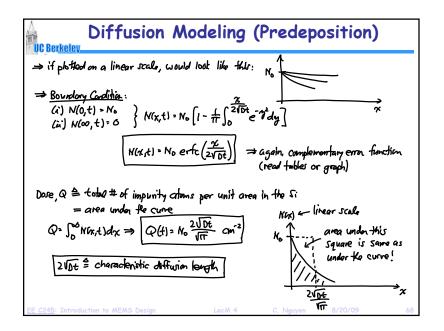


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